Attorney Docket: 026281-0306769 Client Reference: OPP 031059 US

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of:

Confirmation Number: 3859

CHOI

Application No.: 10/735,912

Group Art Unit: 1763

Filed: December 16, 2003

Examiner: LUND, Jeffrie Robert

Title: CHEMICAL VAPOR DEPOSITION APPARATUS AND METHOD

## AMENDMENT UNDER 37 C.F.R. § 1.312

## Mail Stop Issue Fee

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Please consider the following amendment and remarks regarding the above-identified allowed application. It is respectfully submitted that the following amendment does not present any new issues of enablement or allowability, and as such should be entered in its entirety.

There are no amendments to the claims.